

09/806177

JC08 d PCT/PTO 27 MAR 2001

Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)		Atty Docket No. SCHO0051	Serial No.: Unassigned
		Applicant: Schmid	
		Filing Date: Herewith	Group Unassigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
Q.B.	A	WO 95/34798	12/21/95	PCT	G01C	19/56	X	
Q.B.	B	WO 98/15799	4/16/98	PCT	G01C	19/56	X	
Q.B.	C	DE 19530736	8/22/95	DE	G01P	15/125		X

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication	
Q.B.	D	Geiger, W. et al.; <i>New Designs of Micromachined Vibrating Rate Gyroscopes with Decoupled Oscillation Modes</i> ; 1998; Elsevier Science S.A.	
Q.B.	E	Lutz, M. et al.; <i>A Precision Yaw Rate Sensor in Silicon Micromachining</i> ; 1997; IEEE.	
KR	F	Voss, Ralf, et al.; <i>Silicon Angular Rate Sensor for Automotive Applications with Piezoelectric Drive and Piezoresistive Read-Out</i> ; 1997; IEEE.	
Examiner	Date Considered		1/20/04

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.